

**Notice of References Cited**Application No.  
**09/357,264**Applicant(s)  
**Zhang et al.**Examiner  
**Charlotte A. Brown**Group Art Unit  
**1765**

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	DOCUMENT NO.	DATE	NAME	CLASS	SUBCLASS
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U	J.Grossman and D.S. Herman, "A New Etchant for Thin Films of Tantalum and Tantalum Compounds", Journal of Electrochemical Society, Vol. 116, No.5, p.674 and cover page.	5/1969
V	K.S. Indira and B.A. Shenoi, "Chemical Polishing of Metals: A Study", Central Electrochemical Research Institute, p.80-91 including cover page.	8/1973
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